

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

MAR 03 2004

In re the Application of

Seung-un KIM, et al.

Art Unit: 1763

Serial No. 10/084,198 ✓

Examiner: Sylvia MacArthur

Filed: February 28, 2002

*Confirmation No.* 4922

For: APPARATUS AND METHOD FOR SUPPLYING  
CHEMICALS IN CHEMICAL MECHANICAL  
POLISHING SYSTEMS

**AMENDMENT UNDER 37 C.F.R. §1.312**

Commissioner for Patents  
Alexandria, VA 22313-1450  
**MAIL STOP: ISSUE FEE**

Sir:

**INTRODUCTORY COMMENT(S)**

In response to the Examiner's Amendment presented in the Notice of Allowability mailed December 15, 2003, please amend the application identified above as follows: